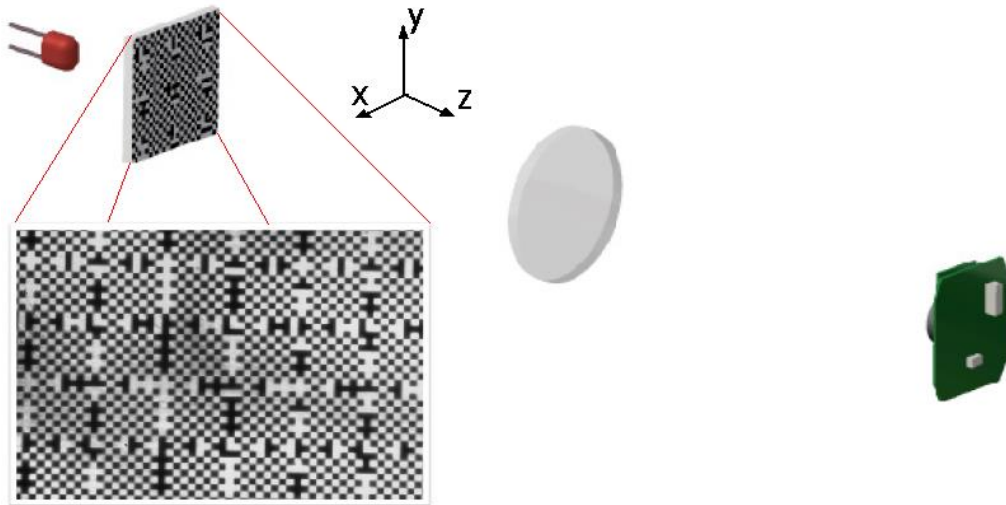
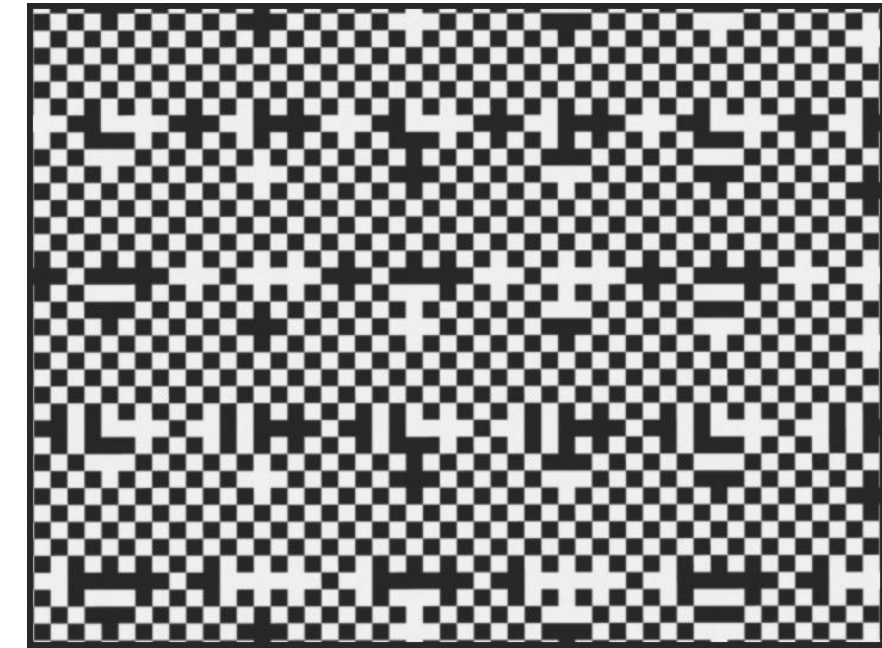


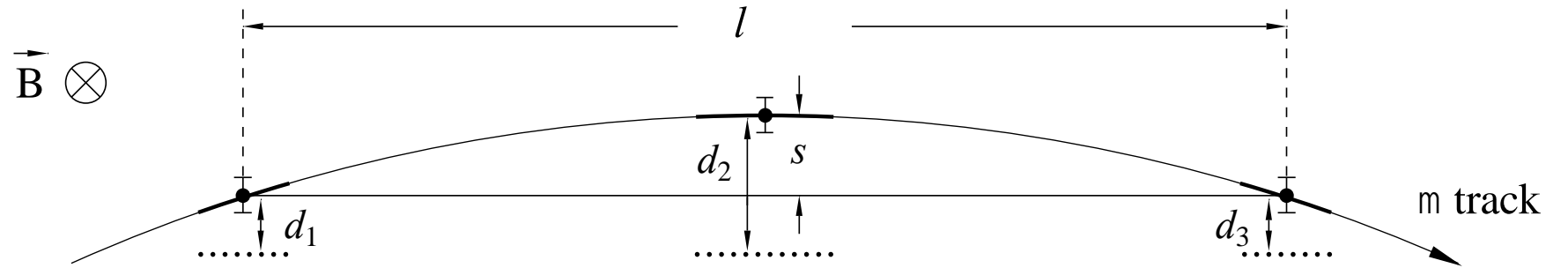
The application of the Rasnik 3-point alignment system in seismic instrumentation

Harry van der Graaf
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Joris van Heijningen
Nelson de Gaay Fortman
Lennart Otemann



Nik|hef

Muon chamber alignment for the L3 and ATLAS experiments at CERN



Muon momentum measurement: Radius of Curvature of track in magnetic field

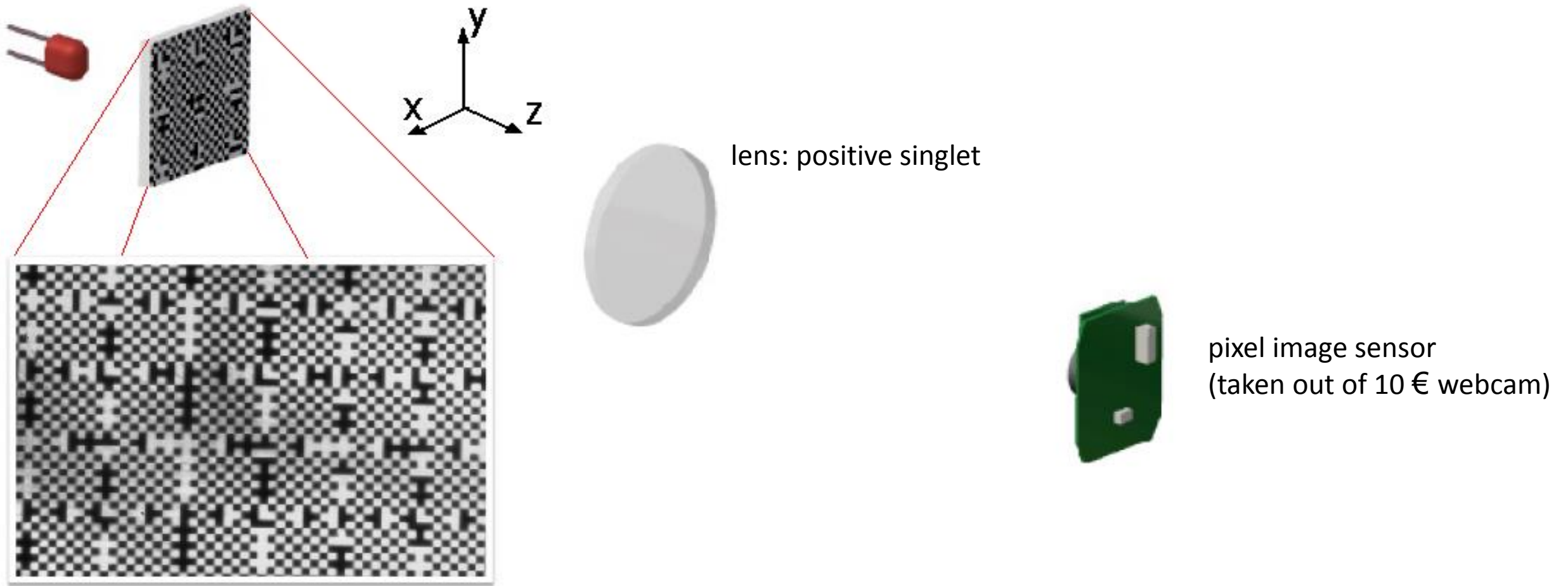
$$p = 0.2998 \times B \times R \text{ (GeV/c)}$$

$$\text{sagitta } s = L^2 / 8R$$

For this, the relative position of the central tracking detector with respect to the two outer chambers must be precisely (of order $10 \mu\text{m}$) known

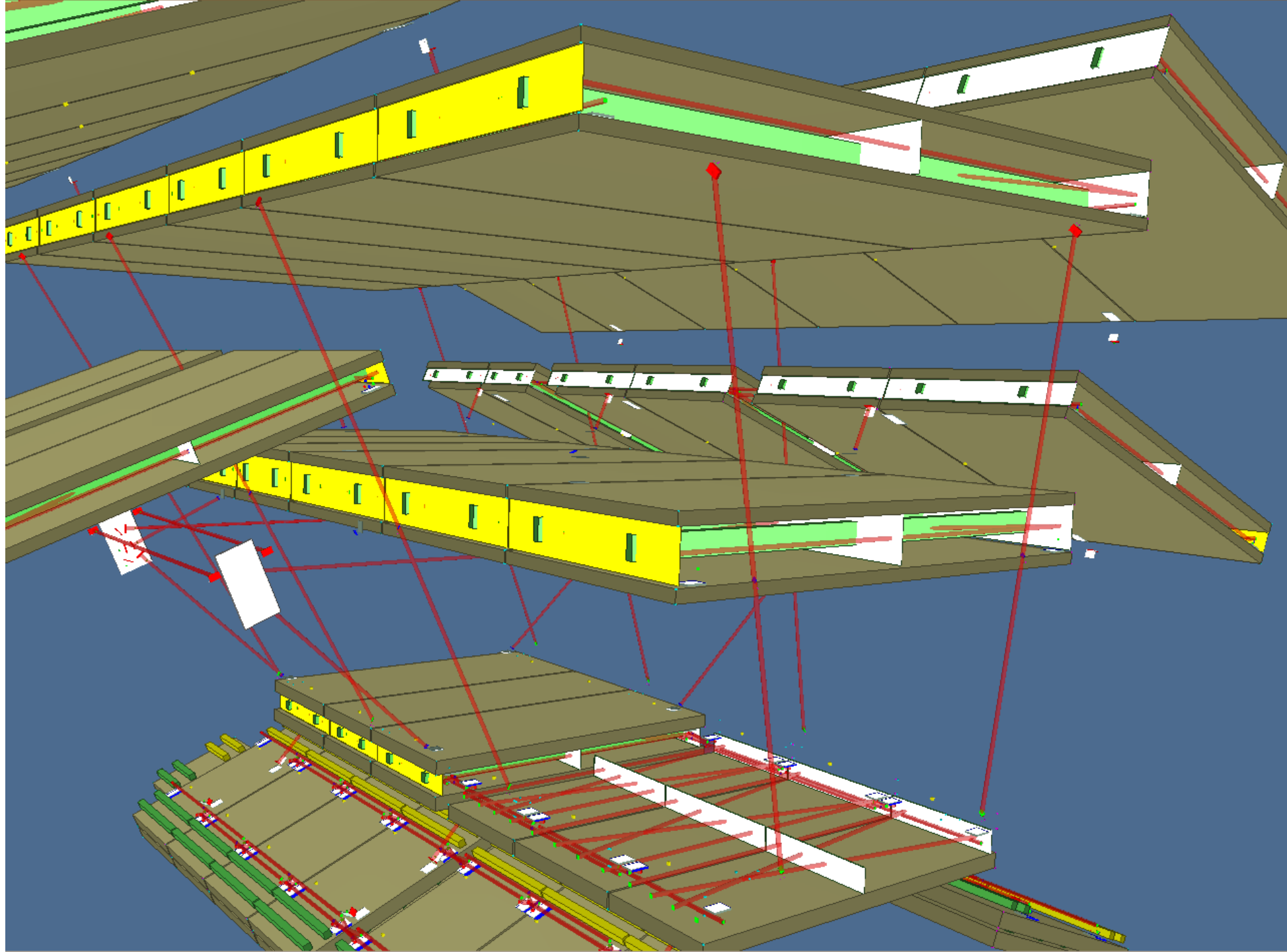
Mechanically this alignment is very hard to obtain, and even harder to maintain due to environment changes in temperature and on/off magnetic field

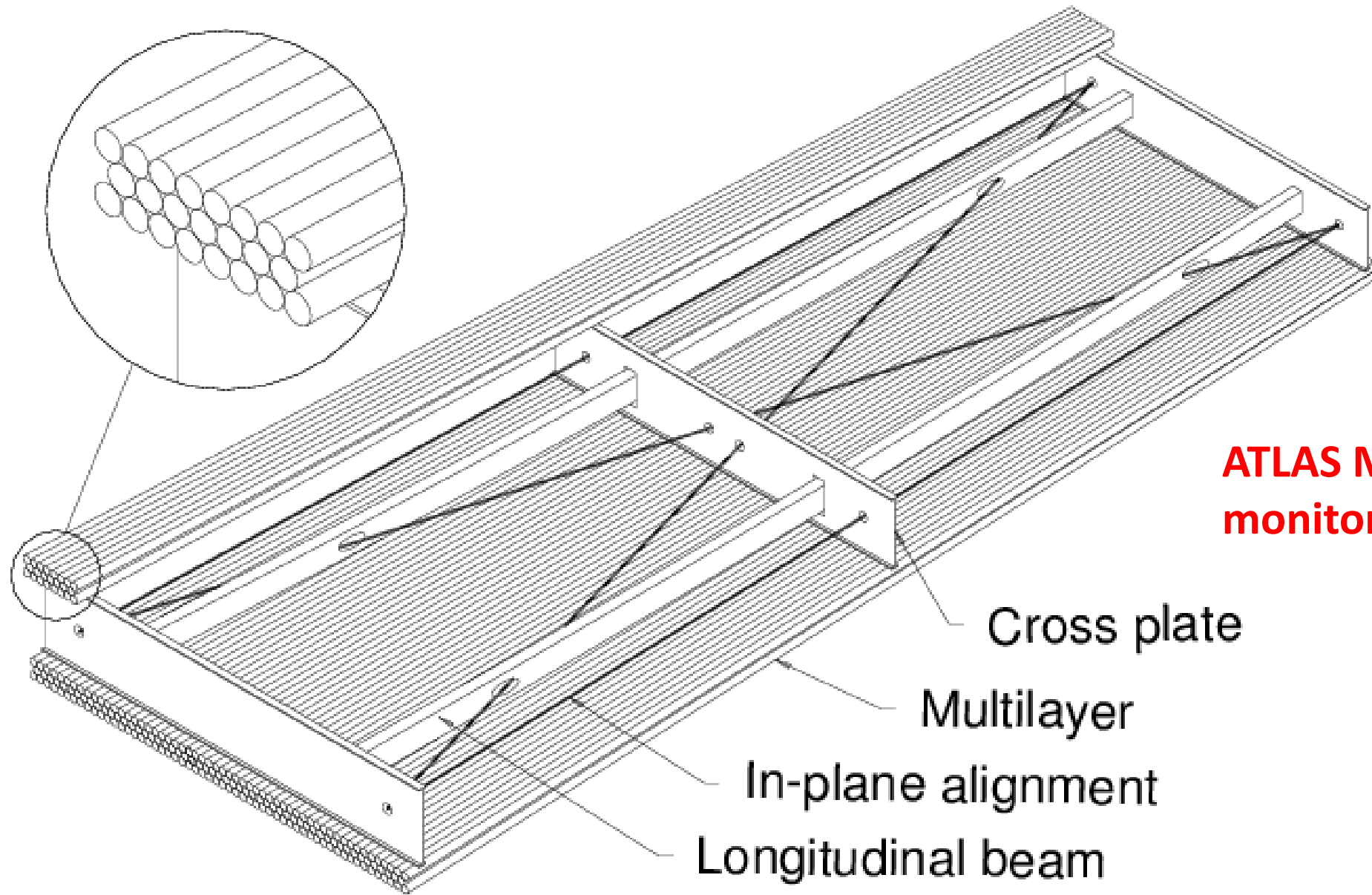
Therefore: **monitoring of alignment**



A relative shift of a mask, lens or image pixel sensor will cause:

- an image-shift-on-the-sensor in X
- an image-shift-on-the-sensor in y
- a change in the image scale S
- a rotation of the image around the optical (Z) axis



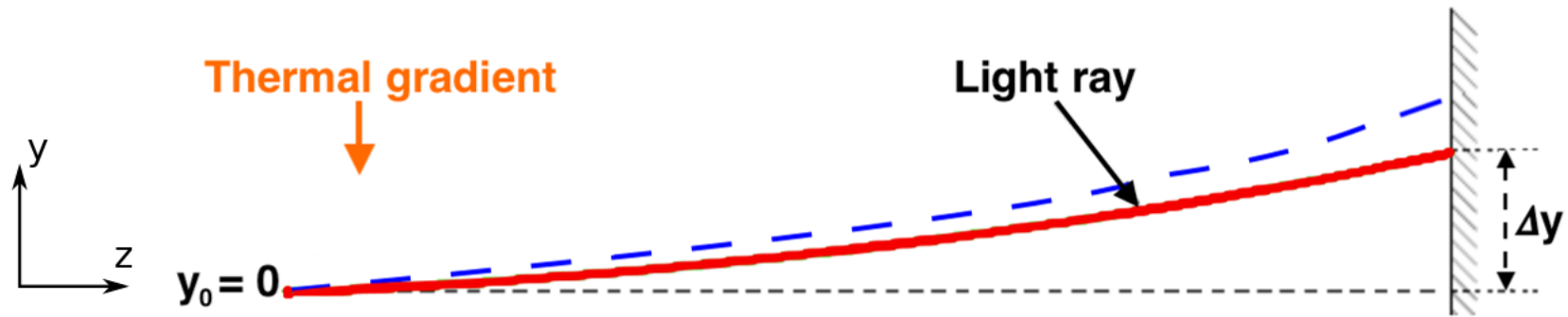


**ATLAS Muon chambers:
monitoring sag and torsion**

In ATLAS, 8000 Rasnik systems are perfectly operational since 2005

The ATLAS Rasniks (6 m distance between mask and sensor) showed sub-um precision

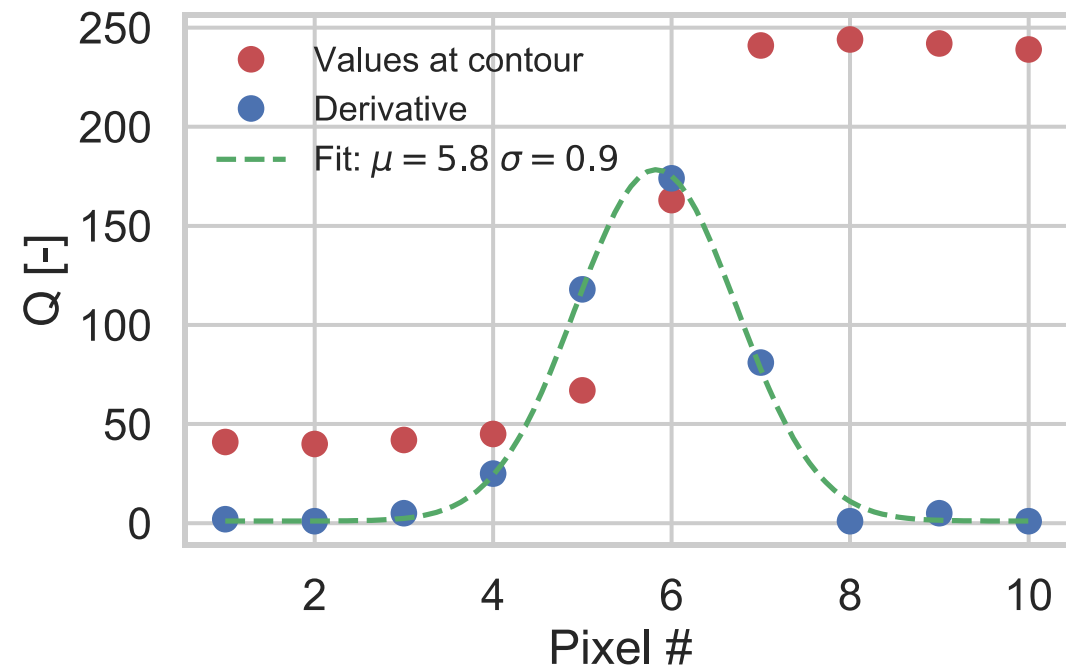
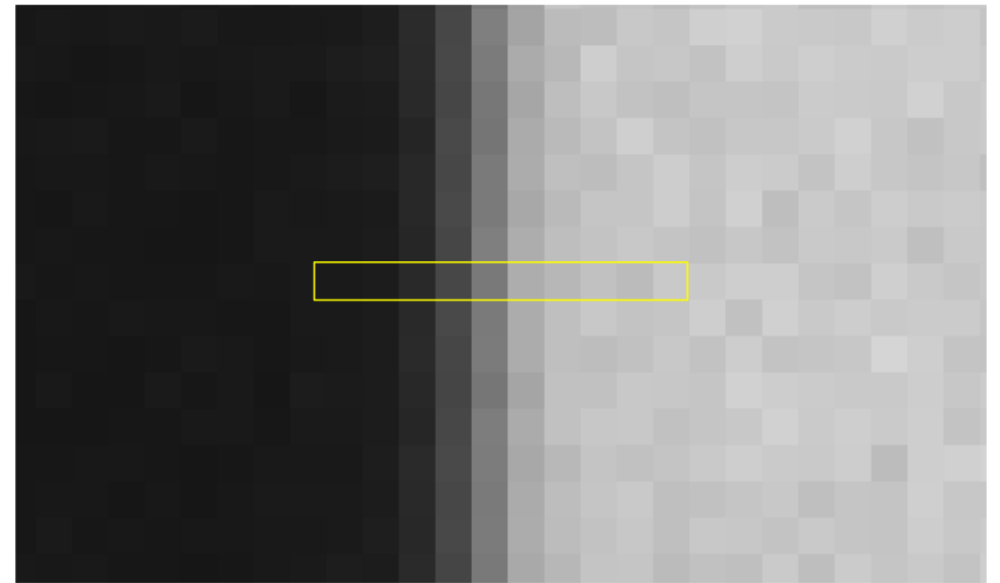
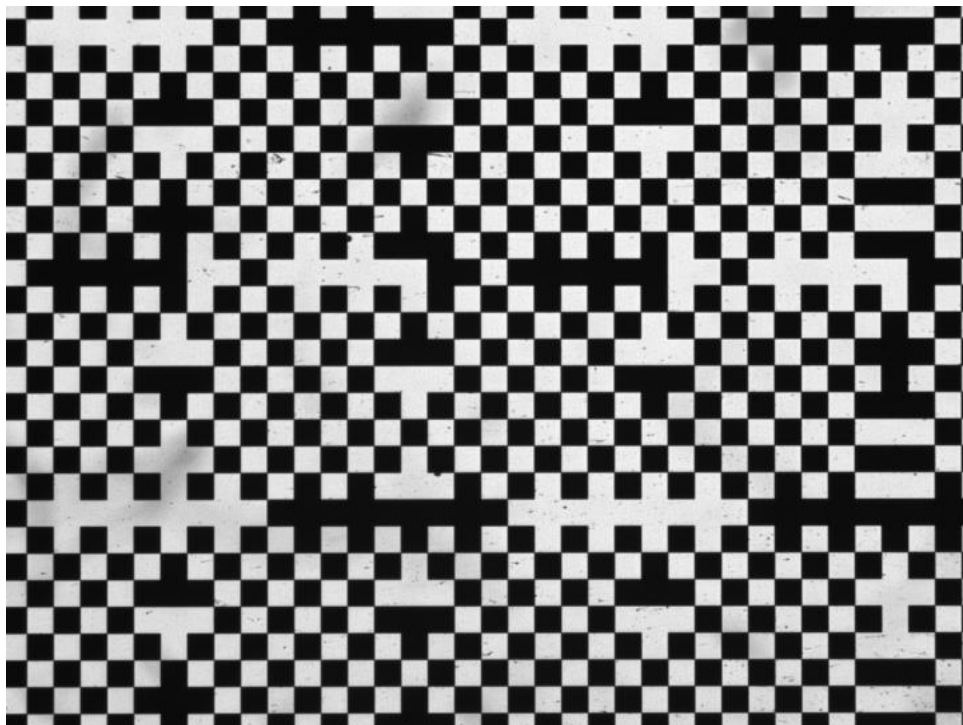
In practical systems, the largest error is due to gradients in air **density**:



So, apply vacuum, or apply shielding of light path

Estimation of precision to be reached:
how well do we measure the image position
on the sensor?

position measurement of
contour (black-white transient)



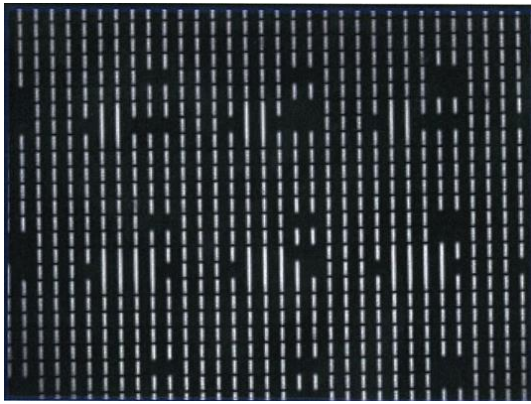
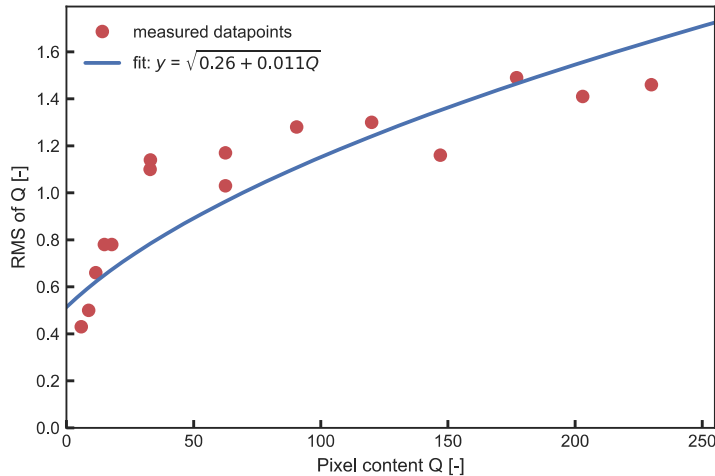


Image differentiated in X
 $Q(n) = Q(n+1) - Q(n-1)$



Pixel noise:
mainly **quantum fluctuations** of light-on-pixel

Standard system:

Sensor: 4 mm x 3 mm

pixel size: 10 μm squares

ChessFiels size: 120 μm squares, optimized for diffraction limited image

Total contour length: 150 mm, both vertical and horizontal

Contour position is sampled each 10 μm , so position is measured 15 k times!

Given width of:

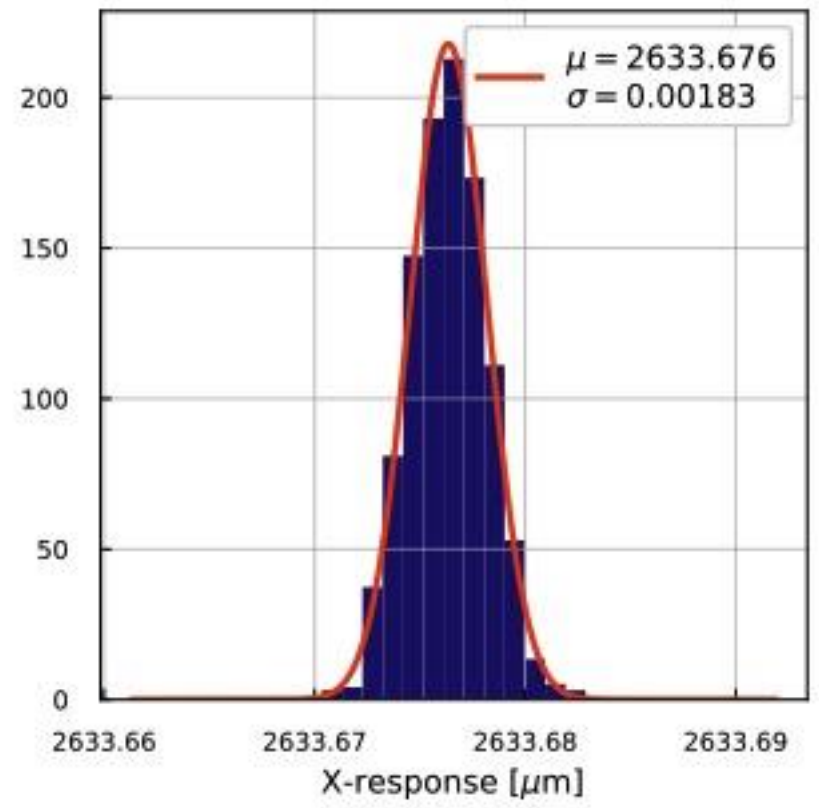
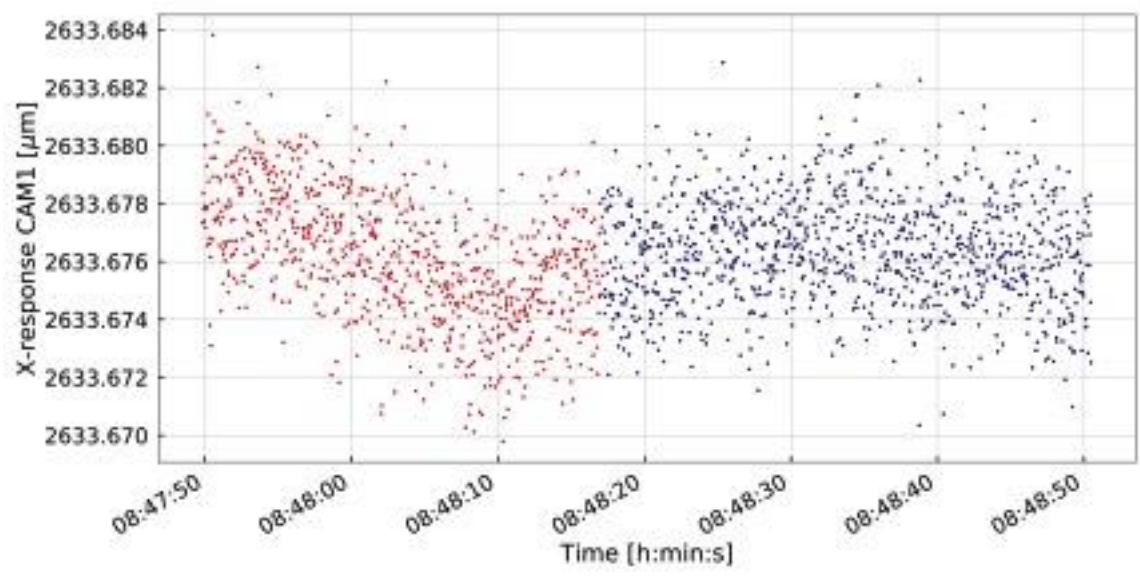
- **Gaussian (diffraction) distribution** and
- **pixel noise**

precision of each sample is 0.2 μm

Expected precision for complete image: 0.2 μm / $\sqrt{15\text{ k}}$ = 1.5 nm

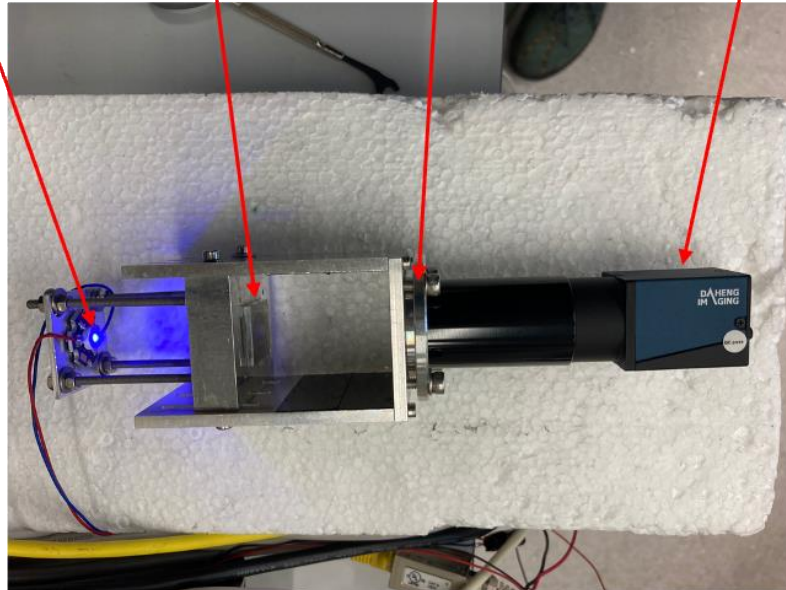
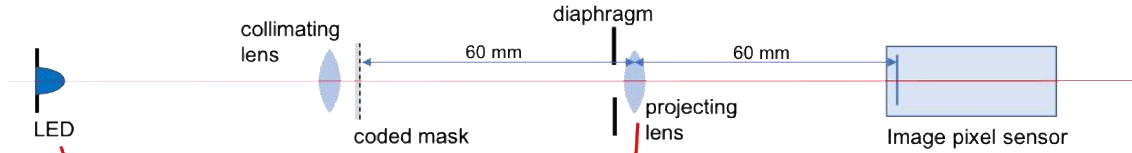
Quality of displacement sensor:

- spatial resolution**
- linearity**
- how many measurements s^{-1} (resolution 'power')**



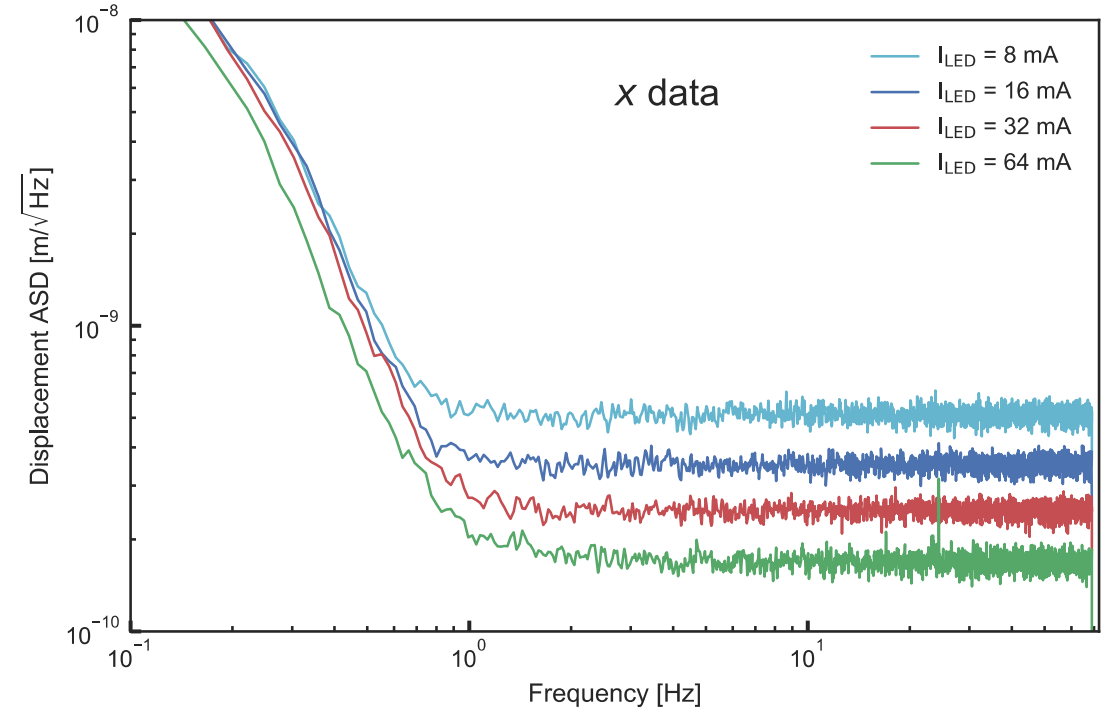
Measurement of spatial resolution

- solid fixation of relative position of mask, objective and sensor
- from multiple images at highest rate



Welch plots, displaying Amplitude Spectral Density (ASD)

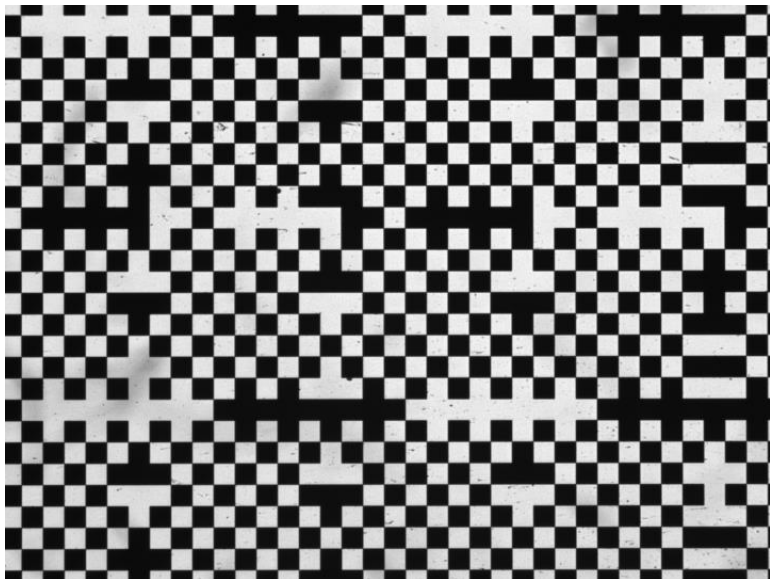
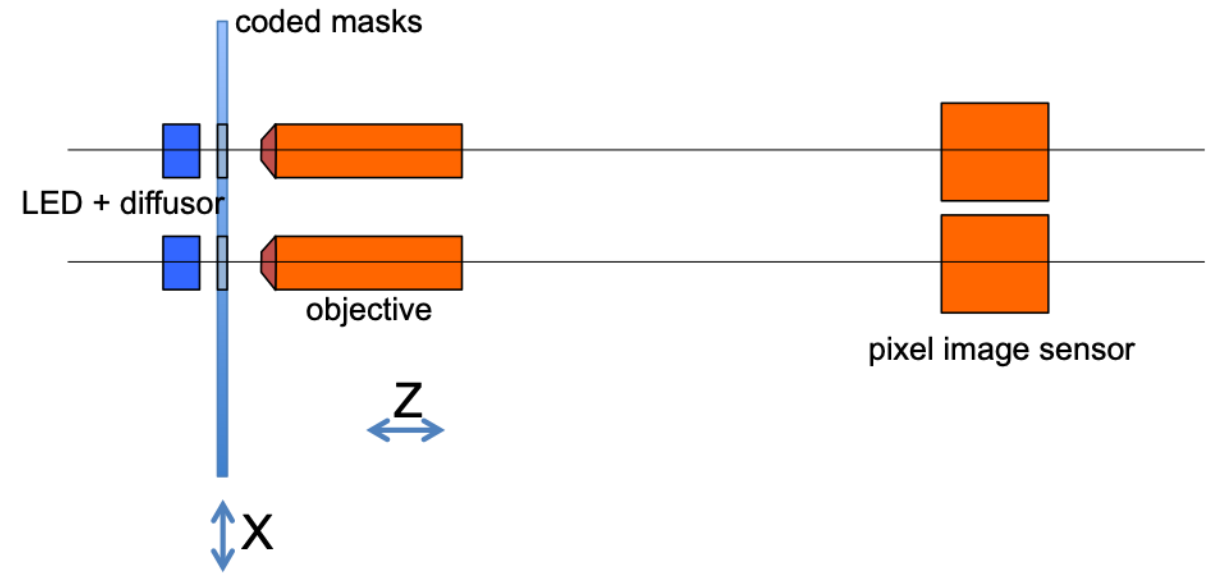
- includes 'resolution power' due to data rate
- filters (still present) thermal and mechanical displacements



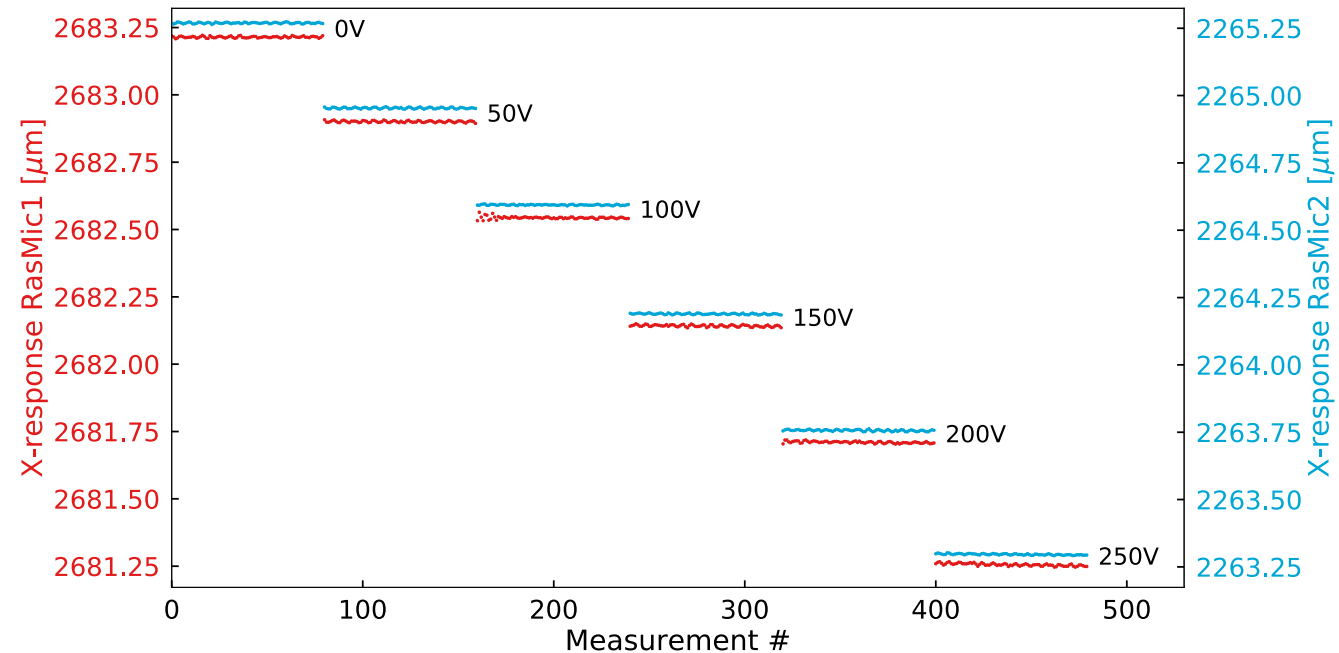
Welch plot of continues data (275 Hz),
in open air

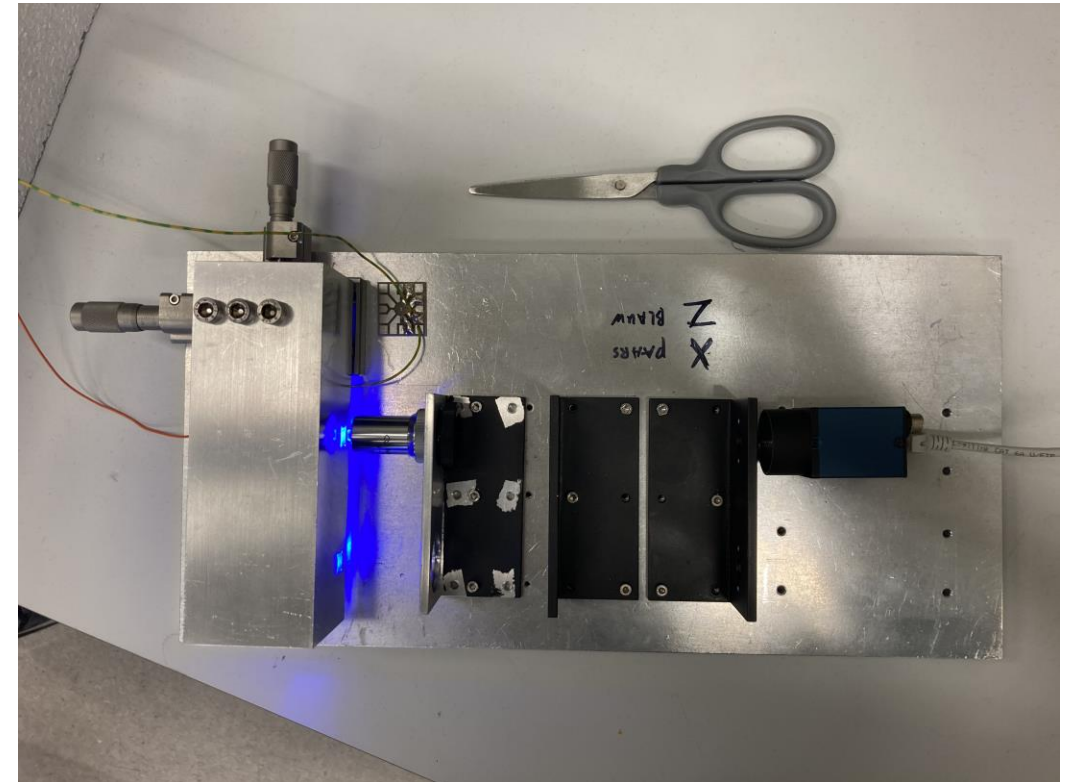
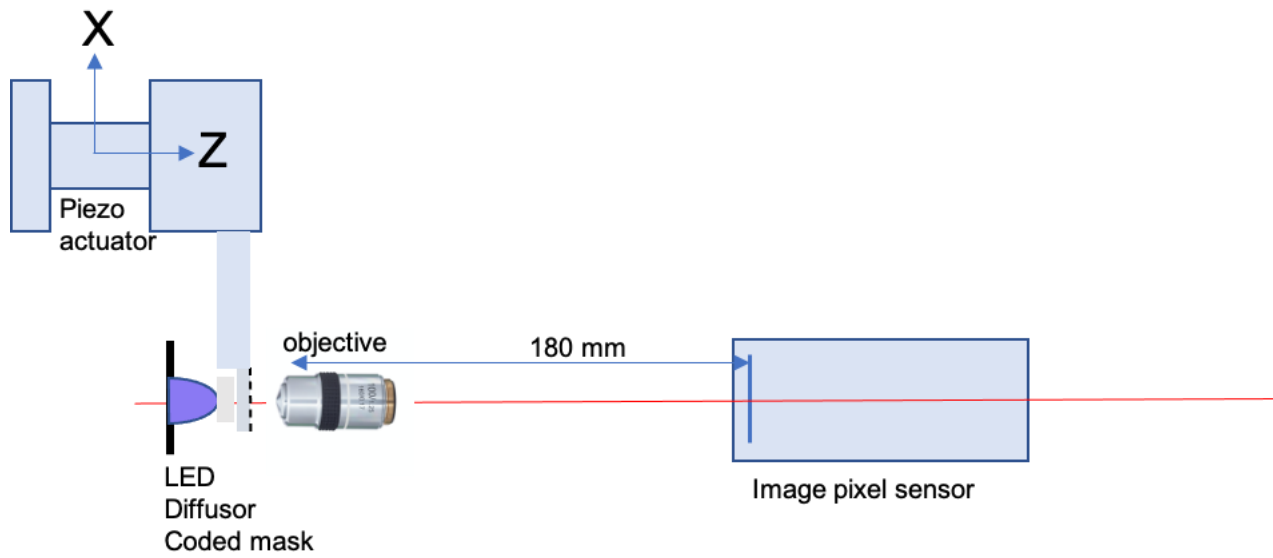
Replace positive lens by microscope objective:
 image displacement increased by factor (magnification)

Measurement of spatial resolution and linearity:
 take two (differential) Rasnik systems:
 both masks are displaced equally by piezo actuator

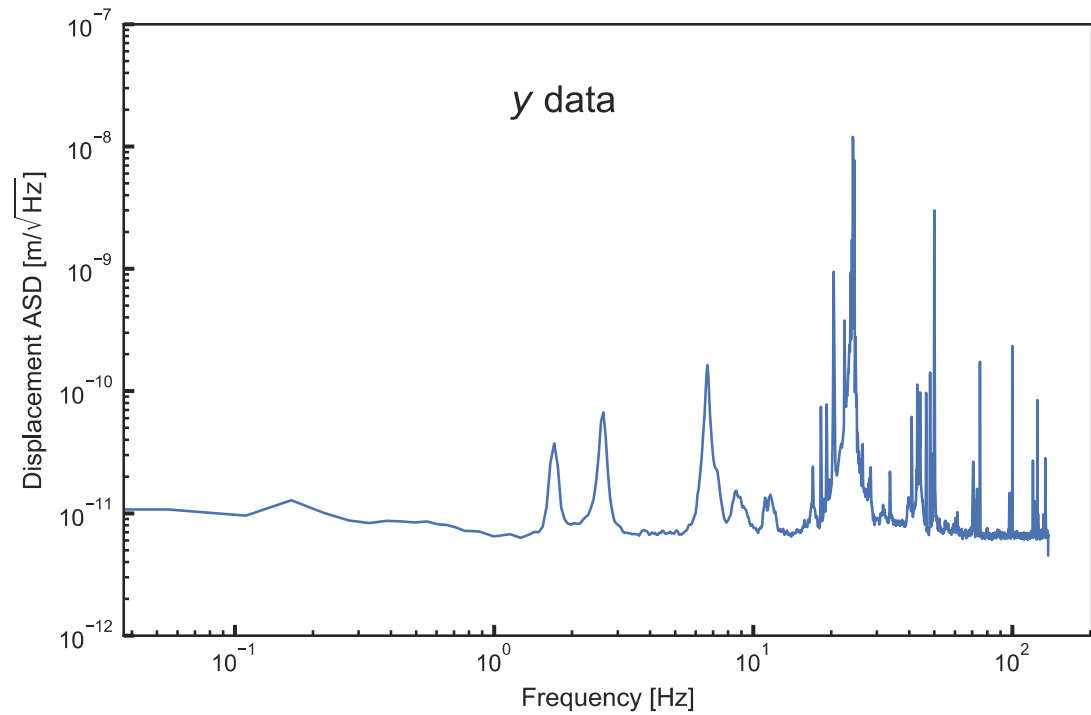
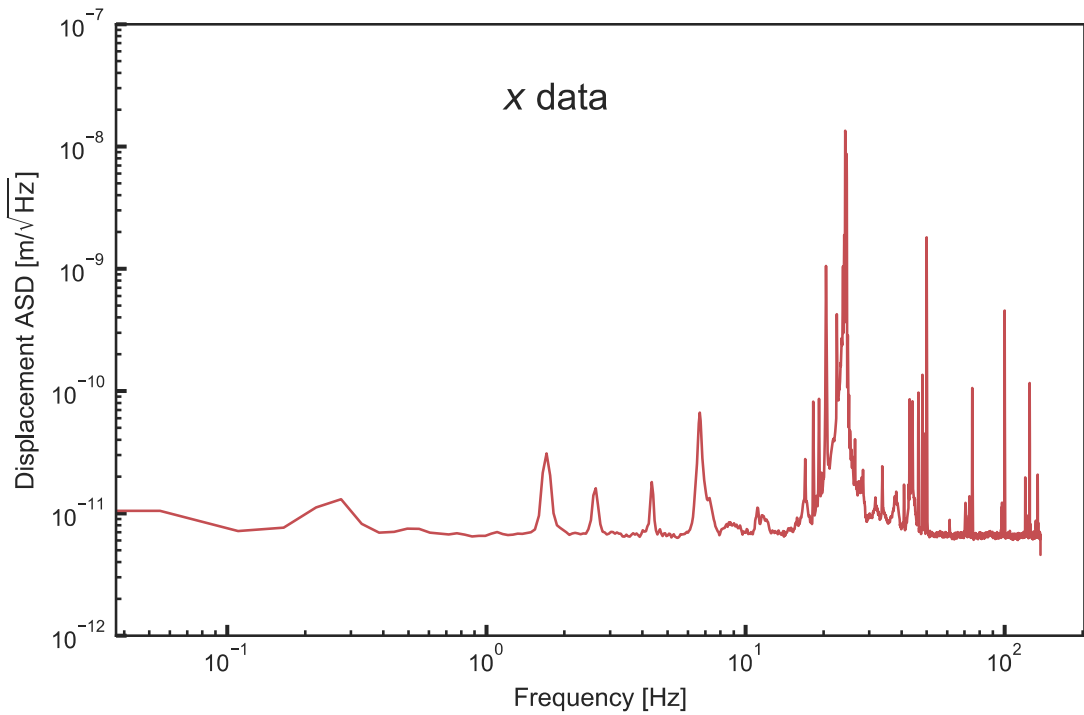


Linearity: determined by mask precision

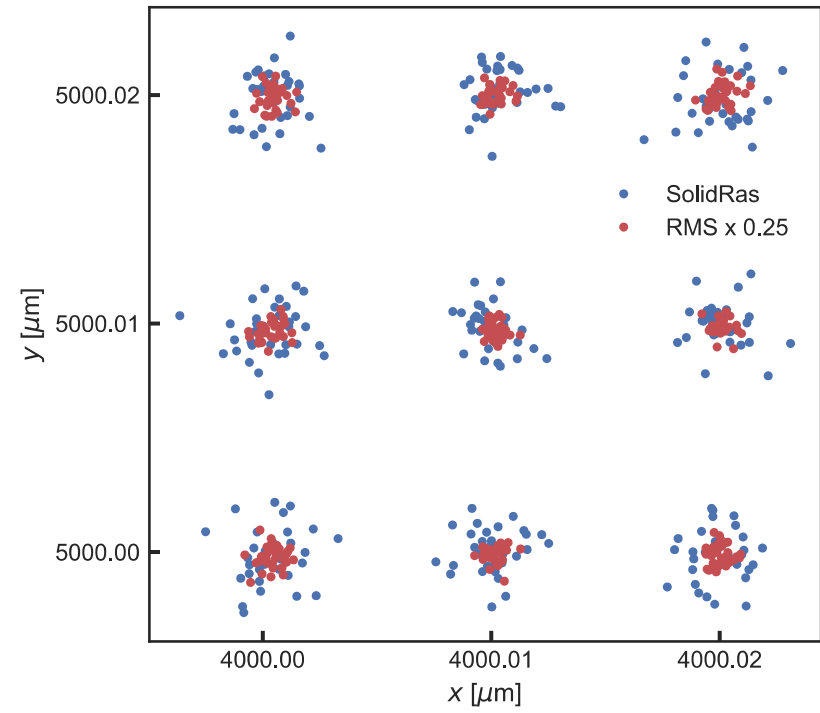
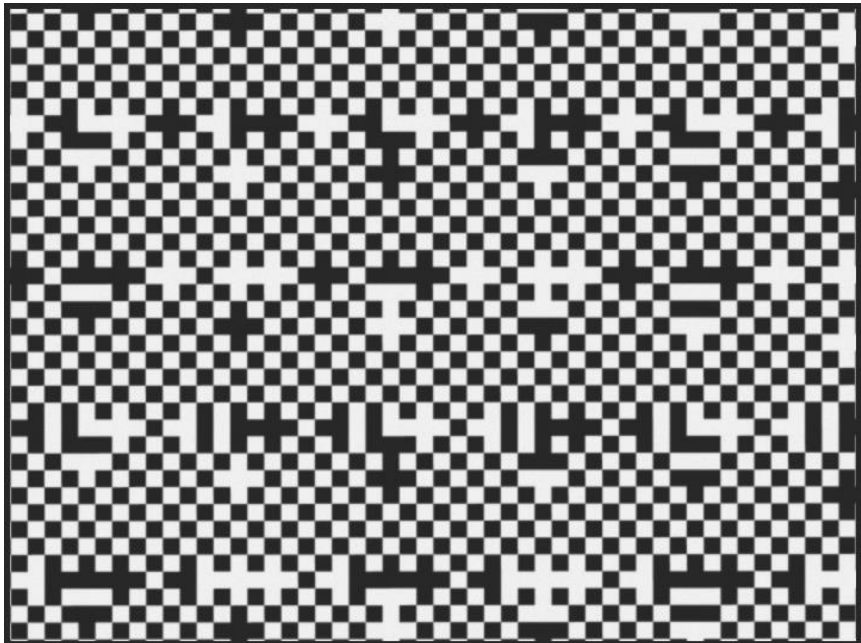
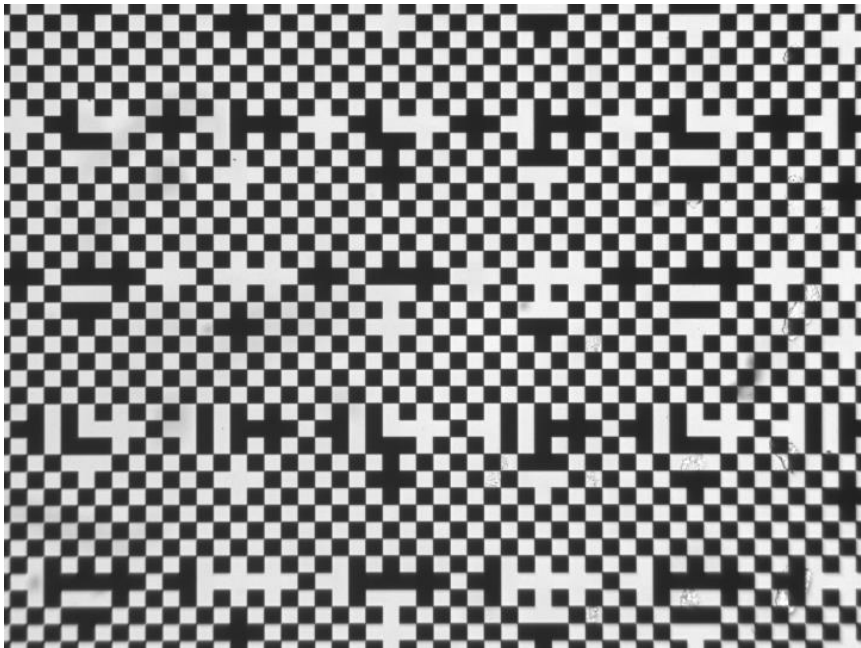




Complete unit was suspended by two thin wires in vacuum tank

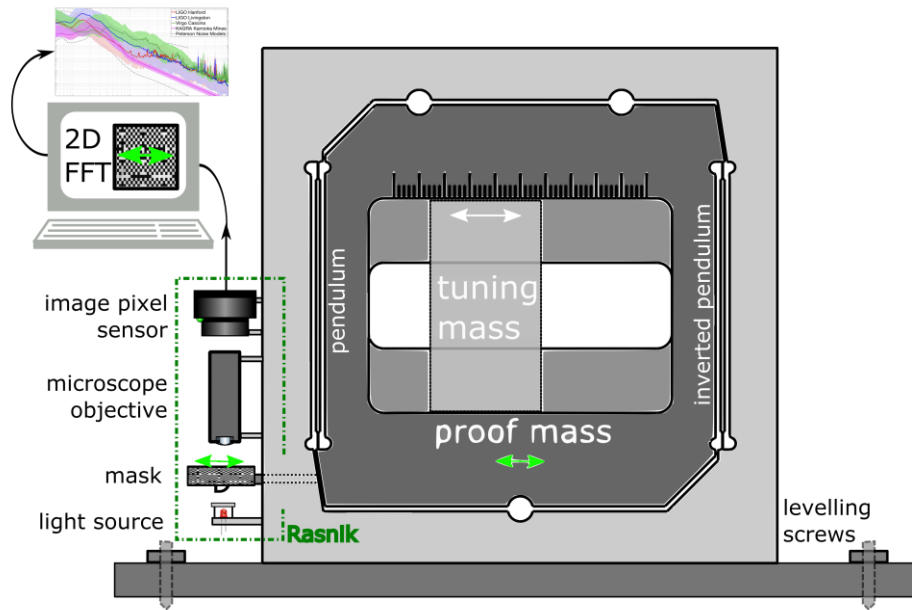


Noise floor level at 7 pm / $\sqrt{\text{Hz}}$



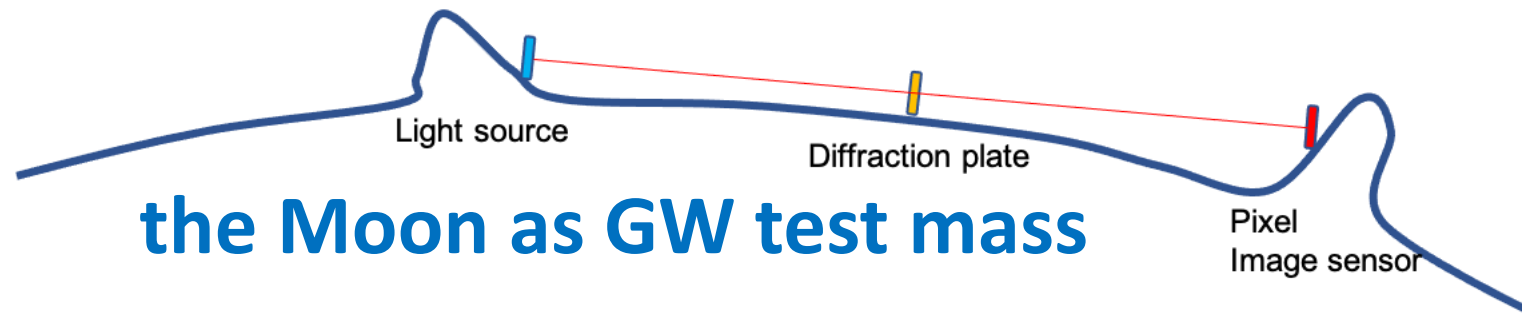
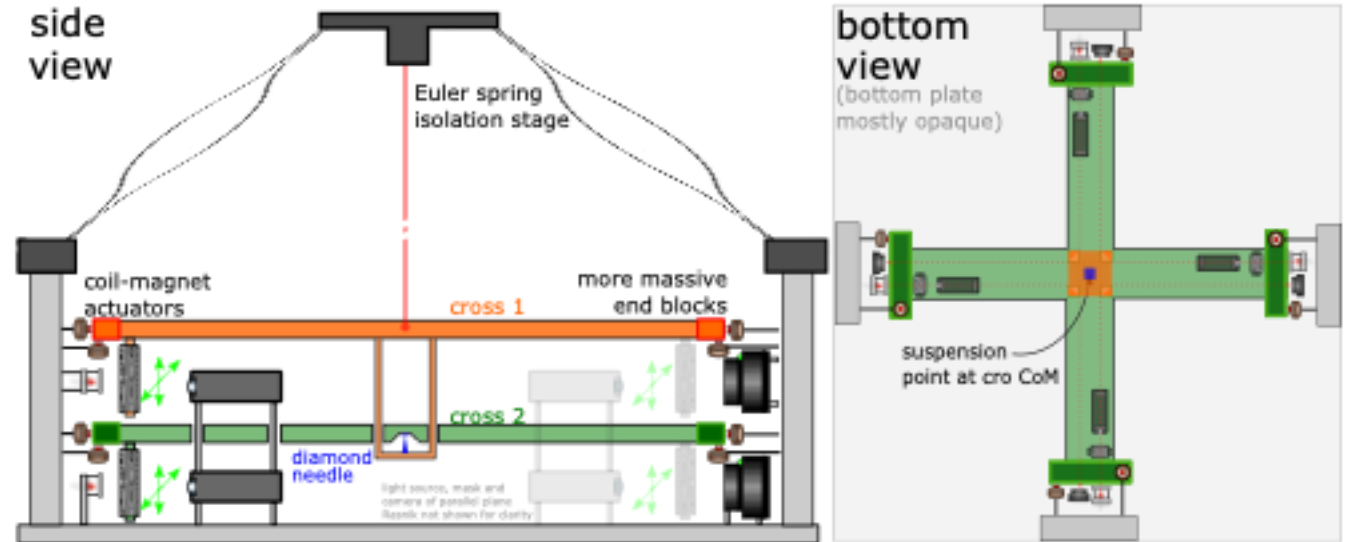
Simulations: revealed non-linearities within a mask period

Applications



(inertial) seismic sensor

(inertial) seismic tilt sensor



the Moon as GW test mass

Conclusions

- Rasnik measures a 2D displacement in the plane of the mask with respect to the optical axis, perpendicular to the mask plane. The optical axis is defined by the fixed-together lens and optical image sensor unit
- systematical linearity error 50 pm or smaller over arbitrarily large dynamic range, in x and y
- only one precision element: the coded mask, available at low cost thanks to MEMS and IC industry
- no cross coupling between output parameters x , y , S and θ_z ; perpendicularity between x and y only defined by the mask
- no calibration required
- straight, analog/digital linear measurement system: no 'lock' control and feedback systems required

- arbitrarily large range of measurement (determined by mask size)
- extremely low $1/f$ noise, and absence of drift; only 3rd order temperature effects
- no special electronics required: a system can be composed of only commercially available CMOS pixel image sensors, CPUs and USB or Ethernet3 networking, and COTS optical components
- (very) low cost: 300 - 3000 € excl. network and CPUs
- light pressure onto the mask acts perpendicular to the directions of interest
- system can operate in air, or in vacuum, and in cryogenic environments if case-specific precautions are taken.

The proven spatial resolution in x and y of Rasnik :	7	pm/ $\sqrt{\text{Hz}}$
is not as good as can be obtained with interferometers	4	fm/ $\sqrt{\text{Hz}}$,
and SQUIDs	0.1 to 3	fm/ $\sqrt{\text{Hz}}$